

Appl. N . 09/785,858

Please replace the Abstract with the following clean replacement Abstract  
in accordance with 37 CFR § 1.121(b)(1)(ii):

*B2*  
The invention includes methods of forming aluminum containing lines having titanium nitride layers thereon. In one aspect, a first layer containing aluminum or an aluminum alloy is formed over a substrate. A second layer is formed containing an alloy of titanium and the aluminum of the first layer. A third layer including titanium nitride is formed and the first, second and third layers are formed into a conductive line. In one aspect, an aluminum containing line is formed utilizing physical vapor deposition of a first layer that contains aluminum or an aluminum alloy. A second layer containing an alloy of titanium and the aluminum of the first layer is formed by physical vapor depositing titanium or a titanium alloy. A third layer containing titanium nitride is formed and the first, second and third layers are photopatterned into a conductive line.

In the Claims

Please replace claims with the following clean version of the entire set of pending claims, in accordance with 37 CFR § 1.121(c)(1)(i). Cancel all previous versions of any pending claim.

A marked up version showing amendments to any claims being changed is provided in one or more accompanying pages separate from this amendment in accordance with 37 CFR § 1.121(c)(1)(ii). Any claim not accompanied by a marked up version has not been changed relative to the immediate prior version.